

High Resolution Scanning electron Microscope

The MIRA3 series is a family of high quality; fully PC-controlled scanning electron microscopes equipped with a Schottky Field Emission electron gun designed for high vacuum or variable pressure operation.

The most important features of this electron microscope are:

- High brightness Schottky emitter for high-resolution/ high-current/ low-noise imaging.
- Unique three-lens wide field optics design offering the variety of working and displaying modes embodying the Tescan proprietary intermediate lens for the beam aperture optimization. Fermentation Control
- Real time In-flight Beam Tracing for the performance and spot optimization integrating the well-established software Electrical Optical Design.
- A powerful In-beam detector of secondary electron located in the objective lens enabling work at very short working distance for high resolution.
- Fast imaging rate.
- High-throughput large area operation e.g. automated particle location and analysis.
- Fully automated microscope set-up including electron optics setup and alignments.
- Sophisticated software for SEM control, image acquisition, achieving, processing and analysis.
- Network operation and built-in remote access/diagnostics.

